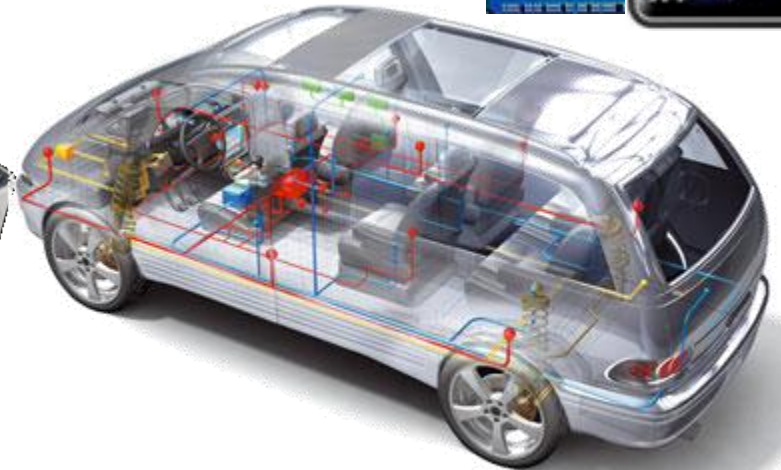
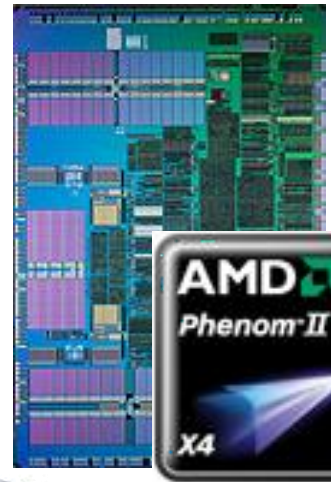


What is SOI?

Do we really need it?

Benefit for Processors, RF and High-Temperature applications



JP Colinge

**Tyndall National Institute
University College Cork
Cork, Ireland**





1- What is SOI ?

2- Bulk MOSFET vs. SOI MOSFET

3- Bulk & SOI MOSFET fundamentals

Types of SOI transistors

4- What is so special about SOI MOSFETs ?

Partially depleted MOSFET

DTMOS/MTCMOS

Fully Depleted SOI

5- Unified body effect representation

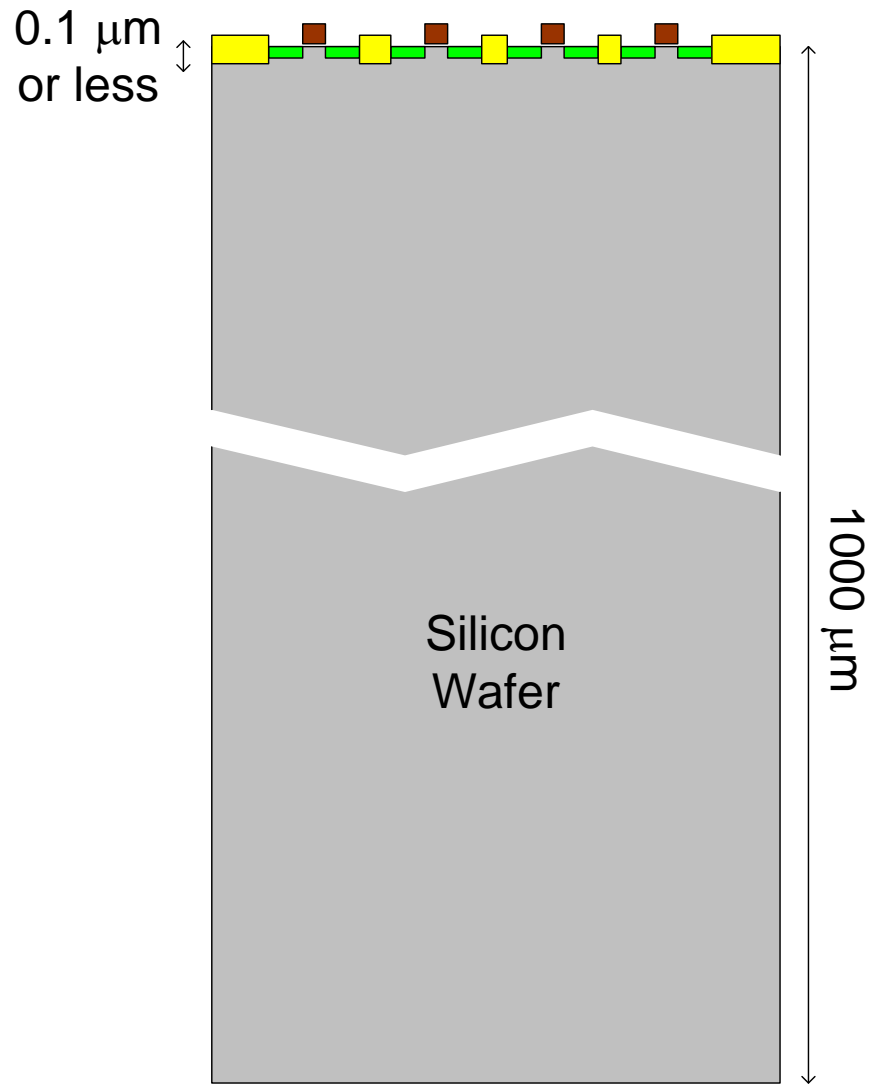
Simple and physics-based comparison of body effect between devices

5- SOI for Microprocessors

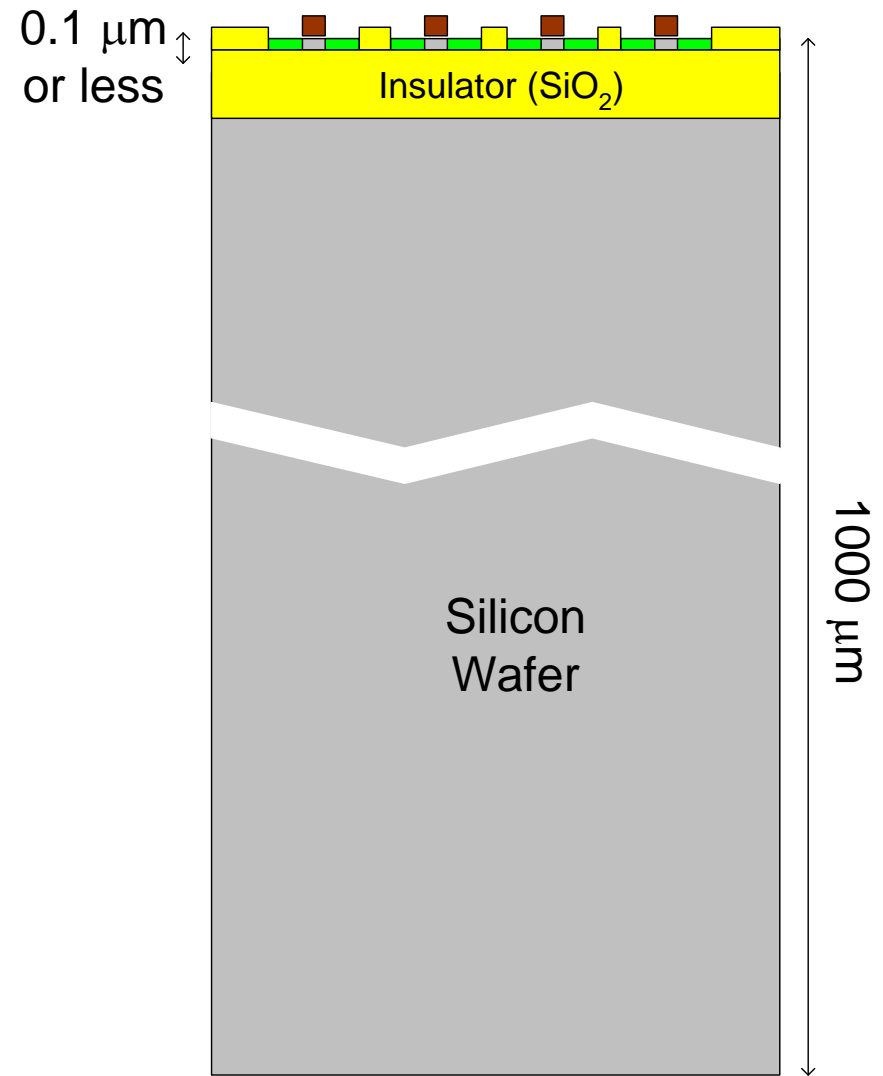
6- SOI for High-Temperature Circuits

7- SOI for RF Circuits

SOI = Silicon On Insulator



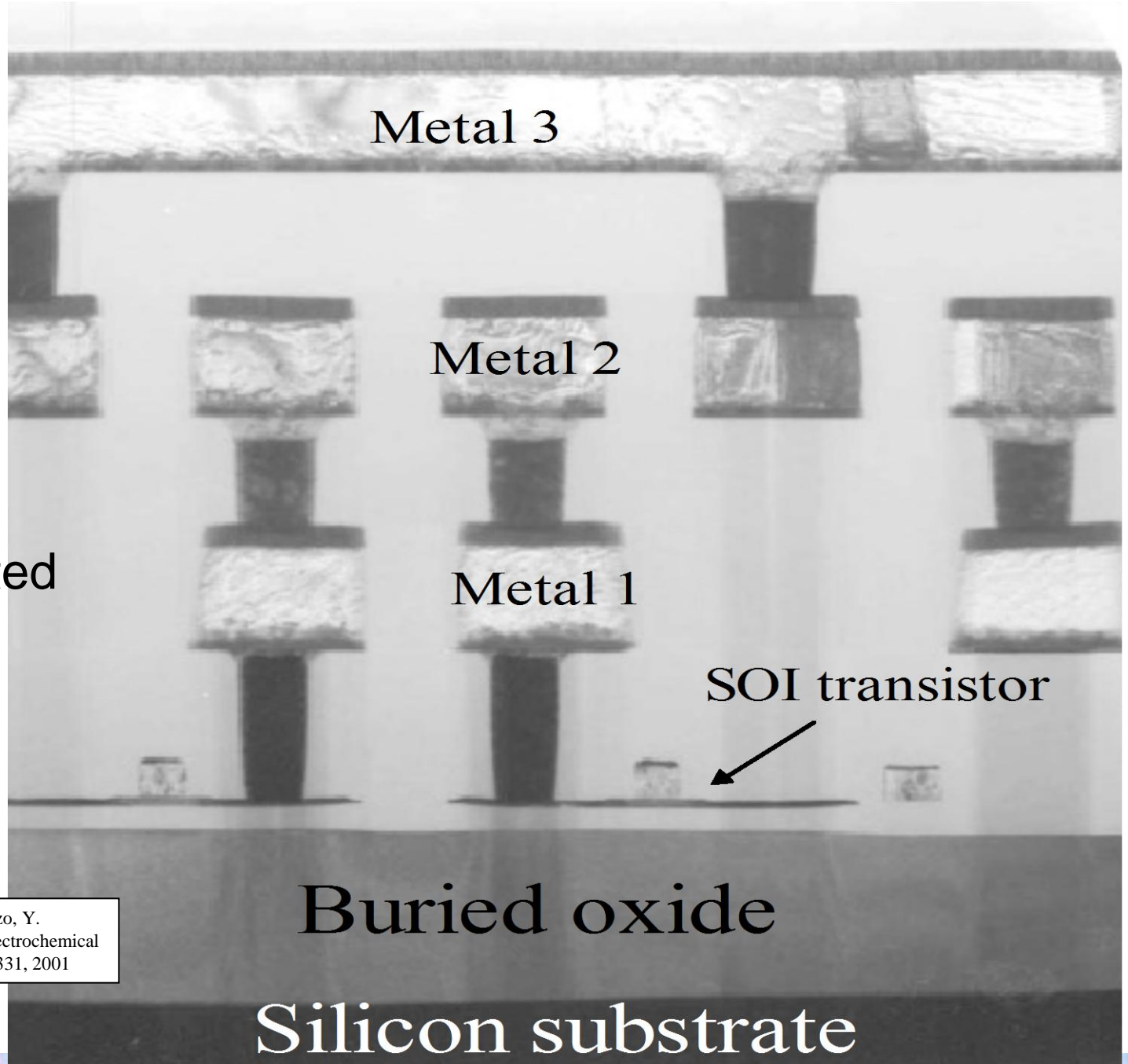
"Bulk" silicon



SOI

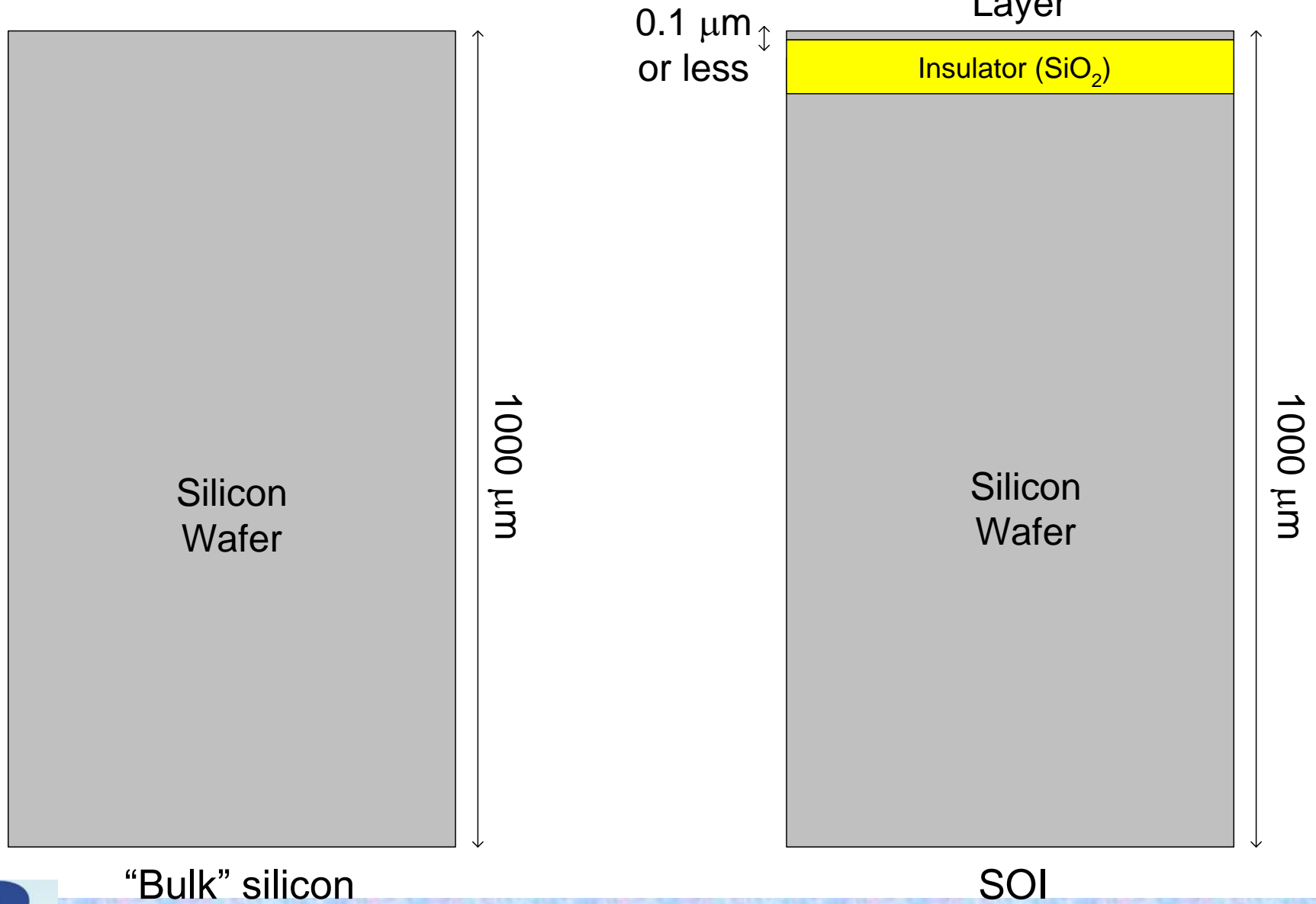
OKI, 2001

Fully Depleted

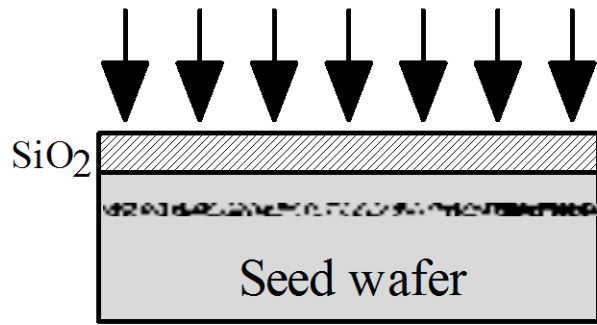


M. Itoh, Y. Kawai, S. Ito, K. Yokomizo, Y.
Katakura, Y. Fukuda, F. Ishikawa, Electrochemical
Society Proceedings, Vol. 2001-3, p. 331, 2001

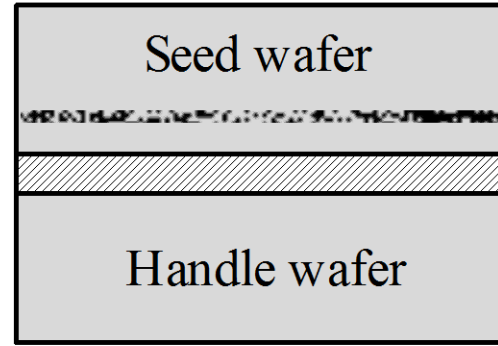
SOI = Silicon On Insulator



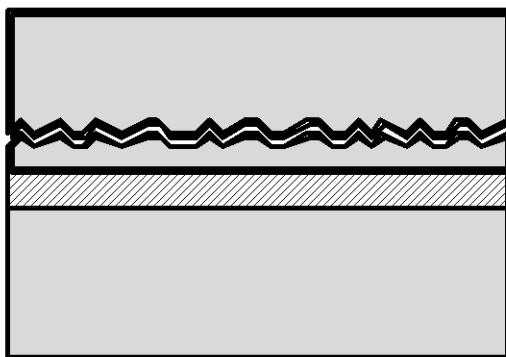
H⁺ implantation



A



B



C

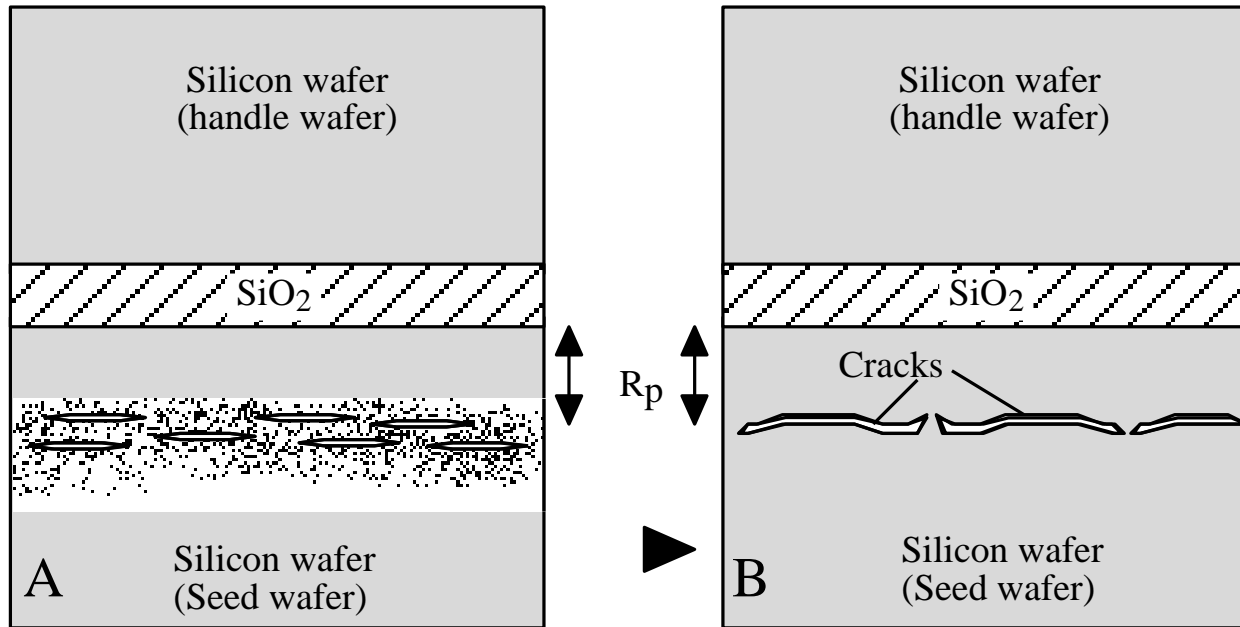


D



SOI Wafer Fabrication

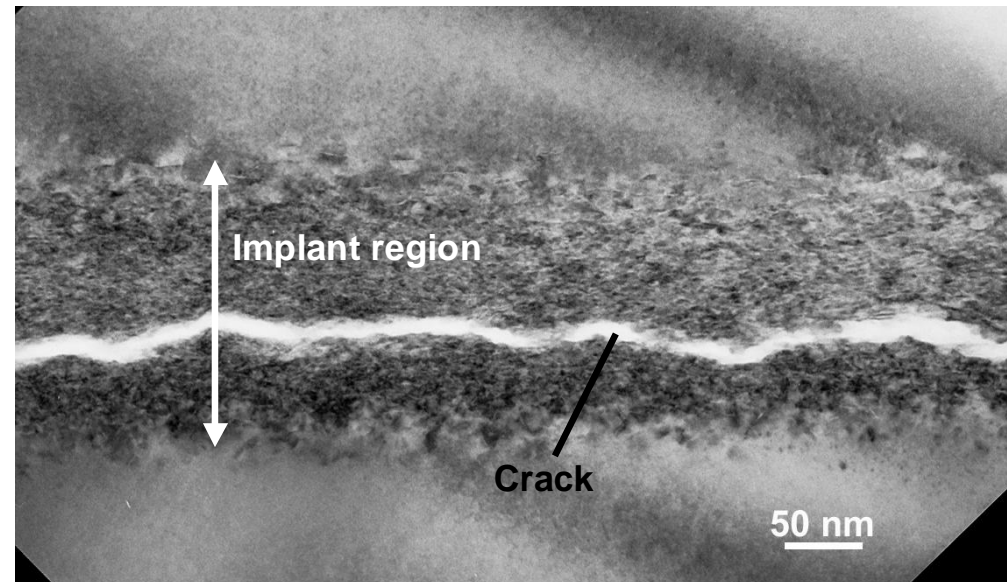
The Smart-Cut[®] process:
A: Hydrogen implantation
B: Wafer bonding
C: Splitting of wafer A
D: Polishing



Formation of cracks near the projected range of a silicon wafer implanted with hydrogen.

A: Bonding of the handle wafer to the seed wafer
 B: Formation of a crack network near the projected range upon annealing.

TEM micrograph of a crack



Product Family	Thin SOI		HM UNIBOND™	Thick SOI		
Products by Applications	Ultra-Thin UNIBOND™ XUT, XUT+	Ultra-Thin UNIBOND™ UTSOI	sSOI	UNIBOND™	UNIBOND™ + Epi	Engineered BSOI
CMOS logic	●	●	●			
Power management ICs				●	●	●
Analog & mixed signal	●			●	●	●
RF & microwave components	●			●	●	
Discrete power devices					●	●
Radiation hard & high temperature ICs	●			●	●	●
Imaging					●	●
M(o)EMS	●			●	●	●
Memories	●					
Silicon photonics	●					
Solid state lighting						

● Current offering



1- What is SOI ?

2- Bulk MOSFET vs. SOI MOSFET

3- Bulk & SOI MOSFET fundamentals

Types of SOI transistors

4- What is so special about SOI MOSFETs ?

Partially depleted MOSFET

DTMOS/MTCMOS

Fully Depleted SOI

5- Unified body effect representation

Simple and physics-based comparison of body effect
between devices

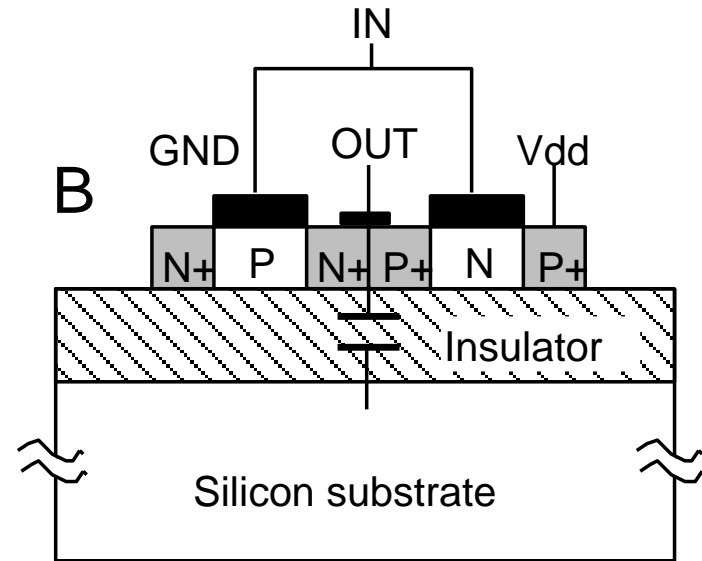
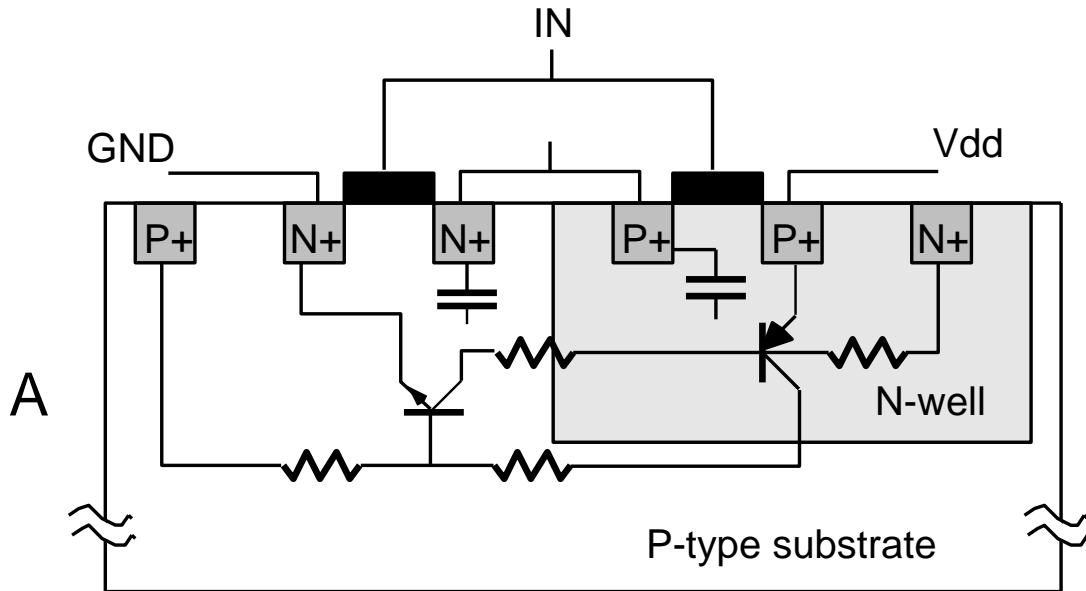
5- SOI for Microprocessors

6- SOI for High-Temperature Circuits

7- SOI for RF Circuits



Latch-up and S&D capacitances

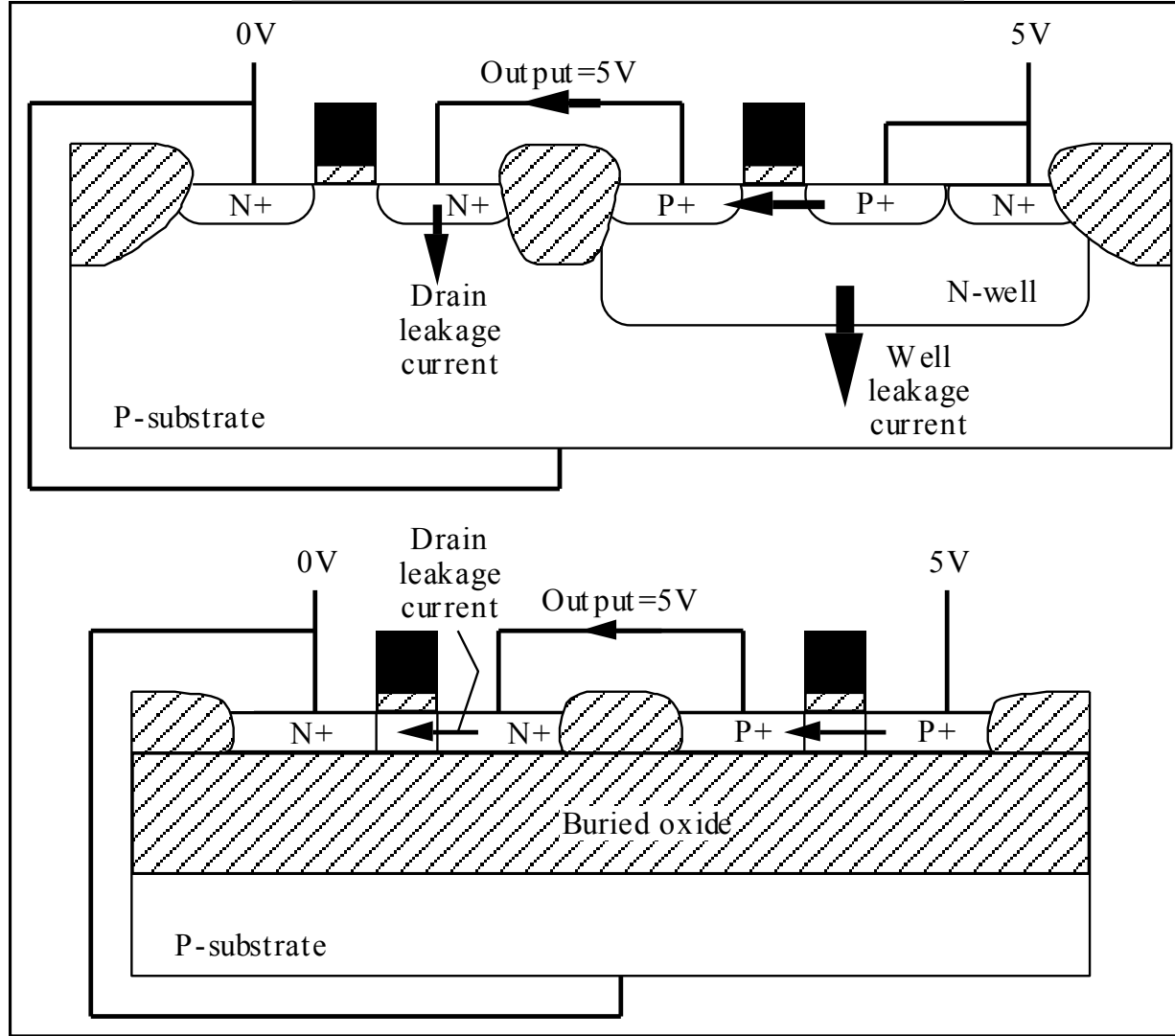


A: Cross section showing the latchup path in a bulk CMOS inverter.

B: Cross section of an SOI CMOS inverter.

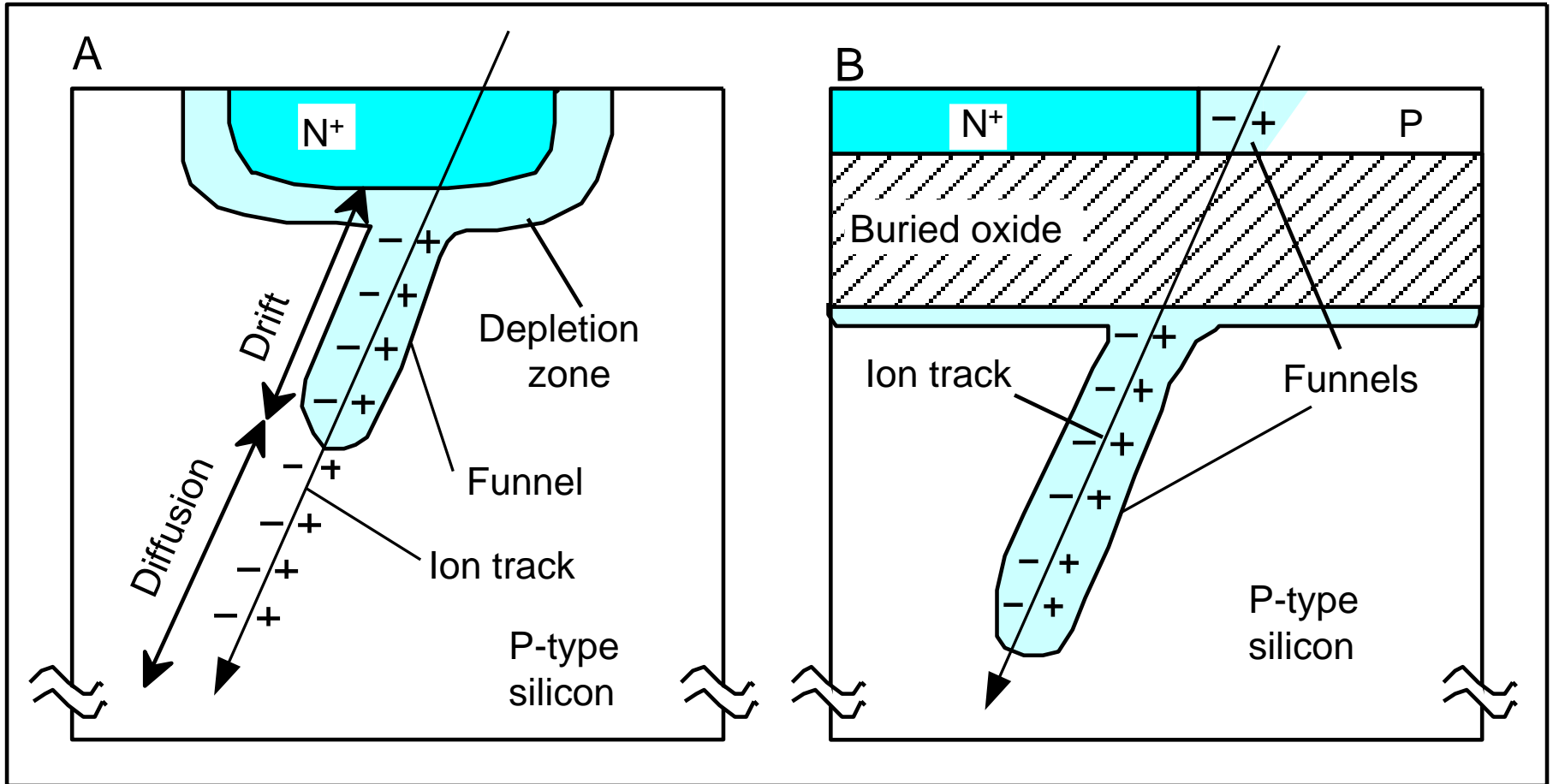
The drain parasitic capacitances are also presented.

Leakage currents



Leakage current paths in bulk (top) and SOI (bottom) CMOS inverters.
No current flow to the substrate is allowed in SOI.

Soft Errors



Ion strike on A: a bulk PN junction, and B: an SOI junction.

1- What is SOI ?

2- Bulk MOSFET vs. SOI MOSFET

3- Bulk & SOI MOSFET fundamentals

Types of SOI transistors

4- What is so special about SOI MOSFETs ?

Partially depleted MOSFET

DTMOS/MTCMOS

Fully Depleted SOI

5- Unified body effect representation

Simple and physics-based comparison of body effect
between devices

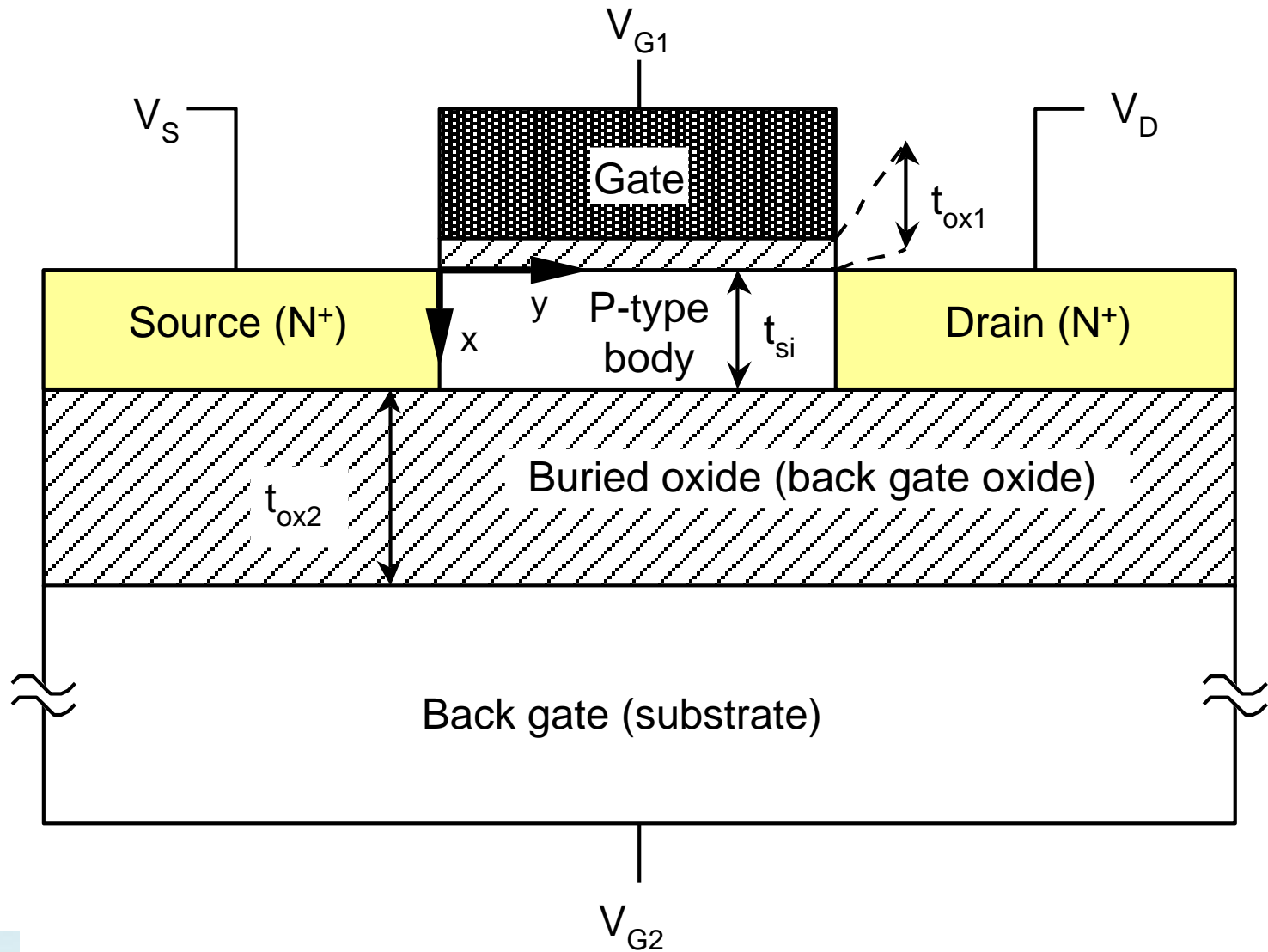
5- SOI for Microprocessors

6- SOI for High-Temperature Circuits

7- SOI for RF Circuits

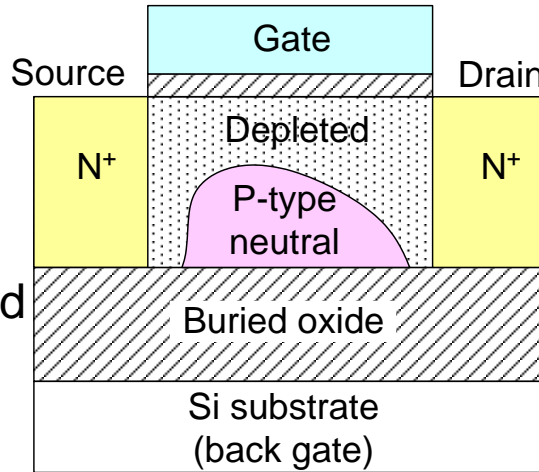


A few definitions....

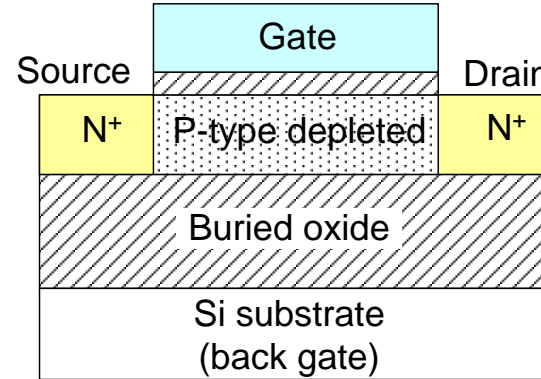


Types of (single-gate) SOI MOSFETs

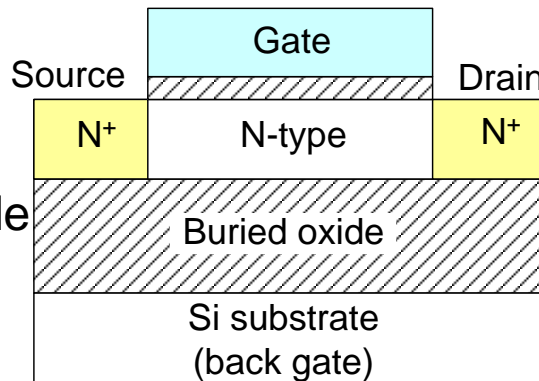
Partially depleted SOI MOSFET



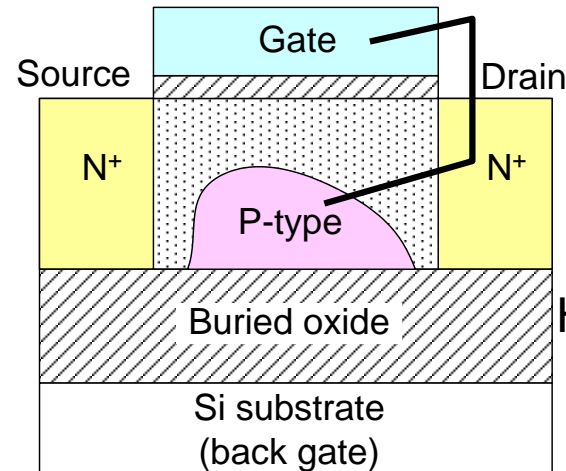
Fully depleted SOI MOSFET



Accumulation-mode SOI MOSFET



Hybrid/MTCMOS/DTMOS FET





1- What is SOI ?

2- Bulk MOSFET vs. SOI MOSFET

3- Bulk & SOI MOSFET fundamentals

Types of SOI transistors

4- What is so special about SOI MOSFETs ?

Partially depleted MOSFET

DTMOS/MTCMOS

Fully Depleted SOI

5- Unified body effect representation

Simple and physics-based comparison of body effect between devices

5- SOI for Microprocessors

6- SOI for High-Temperature Circuits

7- SOI for RF Circuits

Kink Effect: Implications

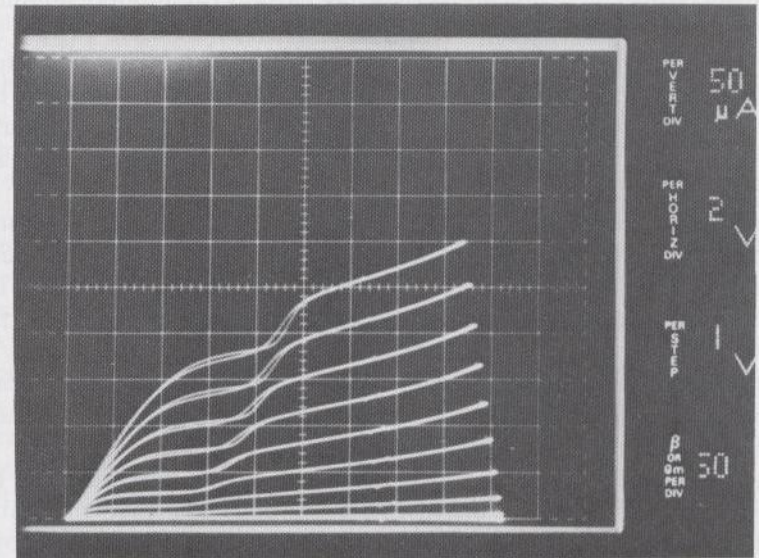
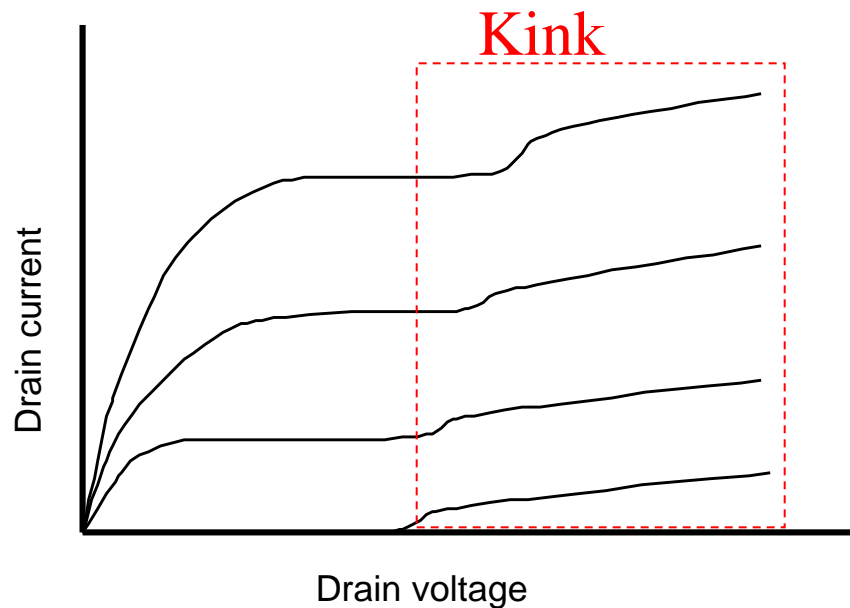


Fig. 86. Characteristic curves of CMOS-SOS devices having $5.0\text{-}\mu\text{m}$ channel lengths and exhibiting two drain saturation regions.

A.C. Ipri AC (1981), "The properties of silicon-on-sapphire substrates, devices, and integrated circuits", Applied Solid-State Sciences, Supplement 2, Silicon Integrated Circuits, Part A, Ed. by. D. Kahng, Academic Press, pp. 253-395, 1981

Good: - increased drain current

Bad: - poor output conductance, low Early voltage
- kink effect generates noise *



1- What is SOI ?

2- Bulk MOSFET vs. SOI MOSFET

3- Bulk & SOI MOSFET fundamentals

Types of SOI transistors

4- What is so special about SOI MOSFETs ?

Partially depleted MOSFET

DTMOS/MTCMOS

Fully Depleted SOI

5- Unified body effect representation

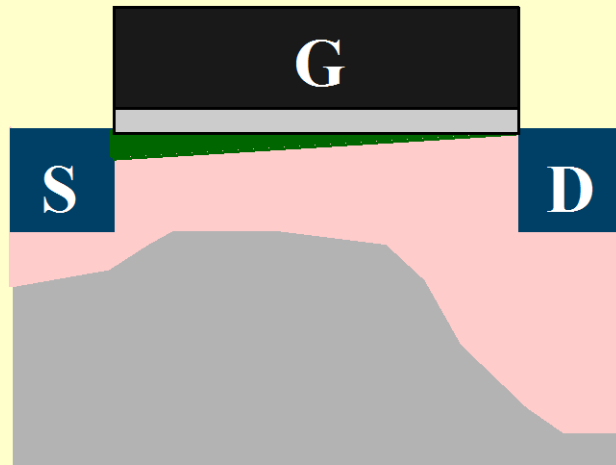
Simple and physics-based comparison of body effect
between devices

5- SOI for Microprocessors

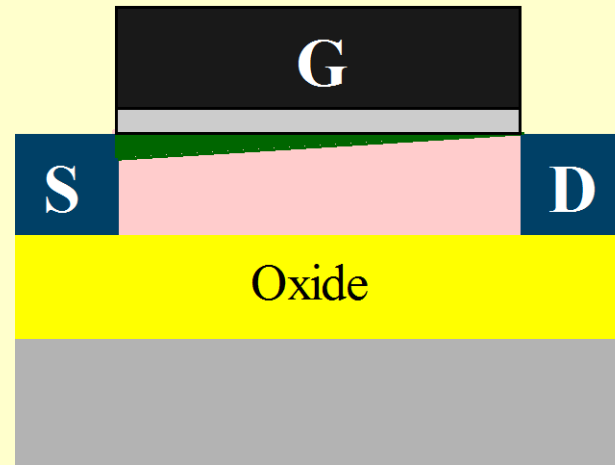
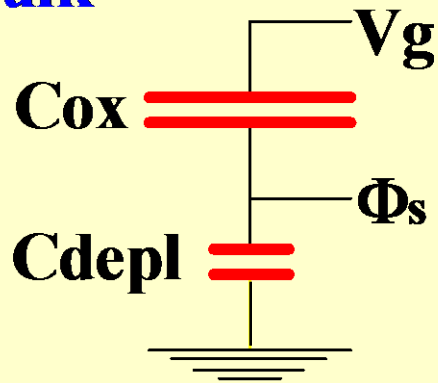
6- SOI for High-Temperature Circuits

7- SOI for RF Circuits

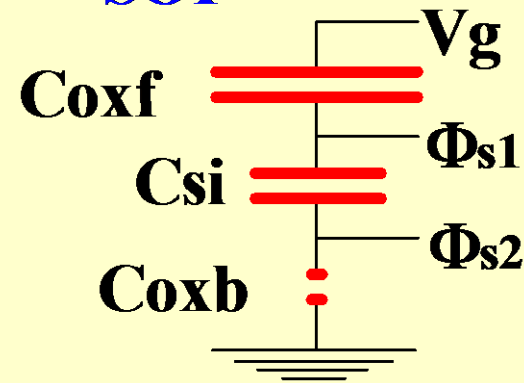
Gate-to-channel coupling; Body Effect



Bulk



SOI



Body factor: $n = \dots 1.05 \dots$ in an FDSOI MOSFET (vs. 1.5 in bulk)

Basic MOSFET equations

•Triode
$$I_D = \mu C_{ox} \frac{W}{L} \left[(V_G - V_{TH}) V_D - \frac{1}{2} n V_D^2 \right]$$

•Saturation
$$I_{Dsat} = \frac{1}{2n} \mu C_{ox} \frac{W}{L} (V_G - V_{TH})^2$$

•Subthreshold swing
$$S = n \frac{kT}{q} \ln(10)$$

•Transconductance/current
$$\frac{g_m}{I_D} = \sqrt{\frac{2\mu C_{ox} W / L}{n I_D}}$$

“A lower n value improves everything”

Gate-to-channel coupling; Body Effect

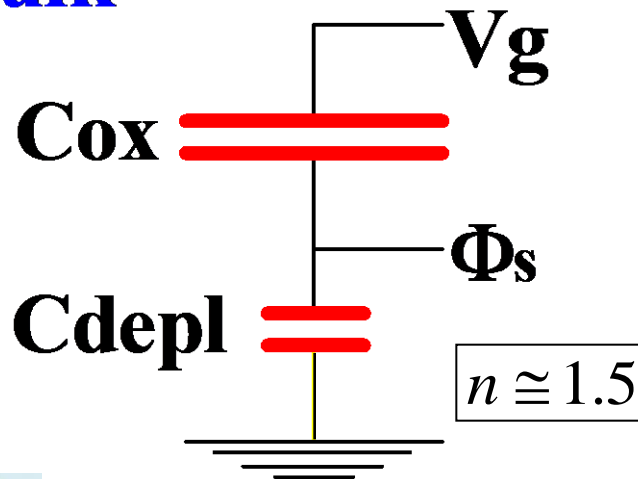
Bulk

$$n \equiv \frac{dV_G}{d\Phi_S} = \frac{C_{ox} + C_{depl}}{C_{ox}} = 1 + \frac{C_{depl}}{C_{ox}} = 1 + \frac{C_{channel\ to\ ground}}{C_{channel\ to\ gate}}$$

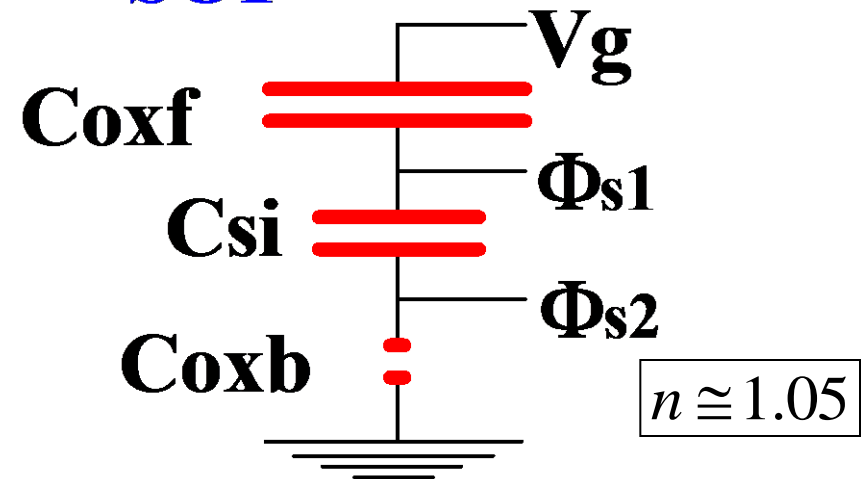
FDSOI

$$n \equiv \frac{dV_G}{d\Phi_S} = \frac{C_{ox} + C_{depl}}{C_{ox}} = 1 + \frac{C_{si}C_{ox2}}{C_{ox1}(C_{si} + C_{ox2})} = 1 + \frac{C_{channel\ to\ ground}}{C_{channel\ to\ gate}}$$

Bulk



SOI



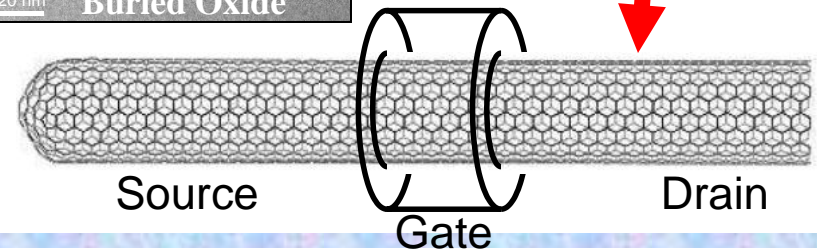
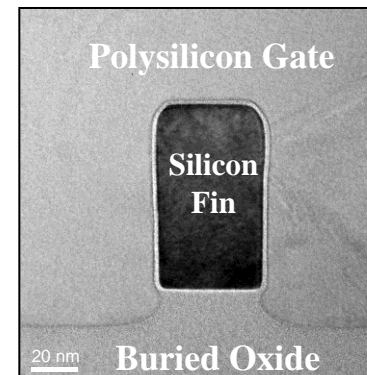
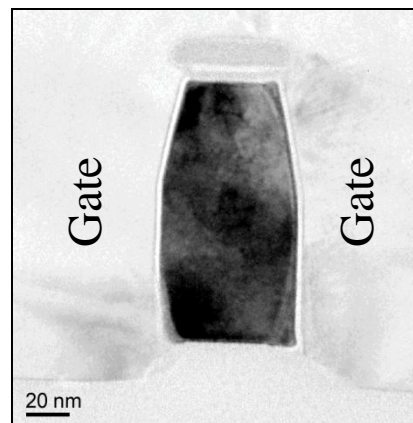
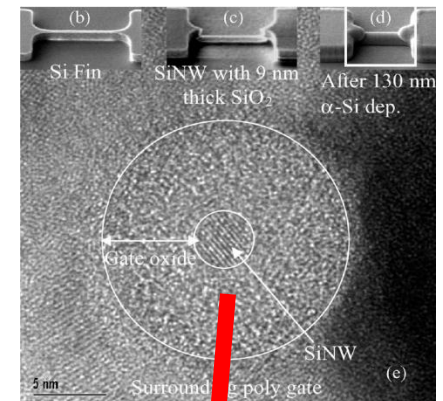
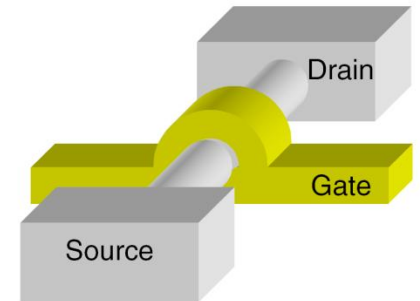
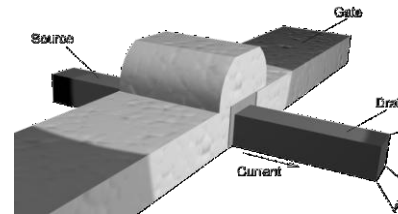
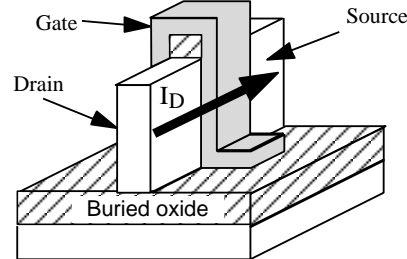
End of Roadmap Research

“1 Gate”

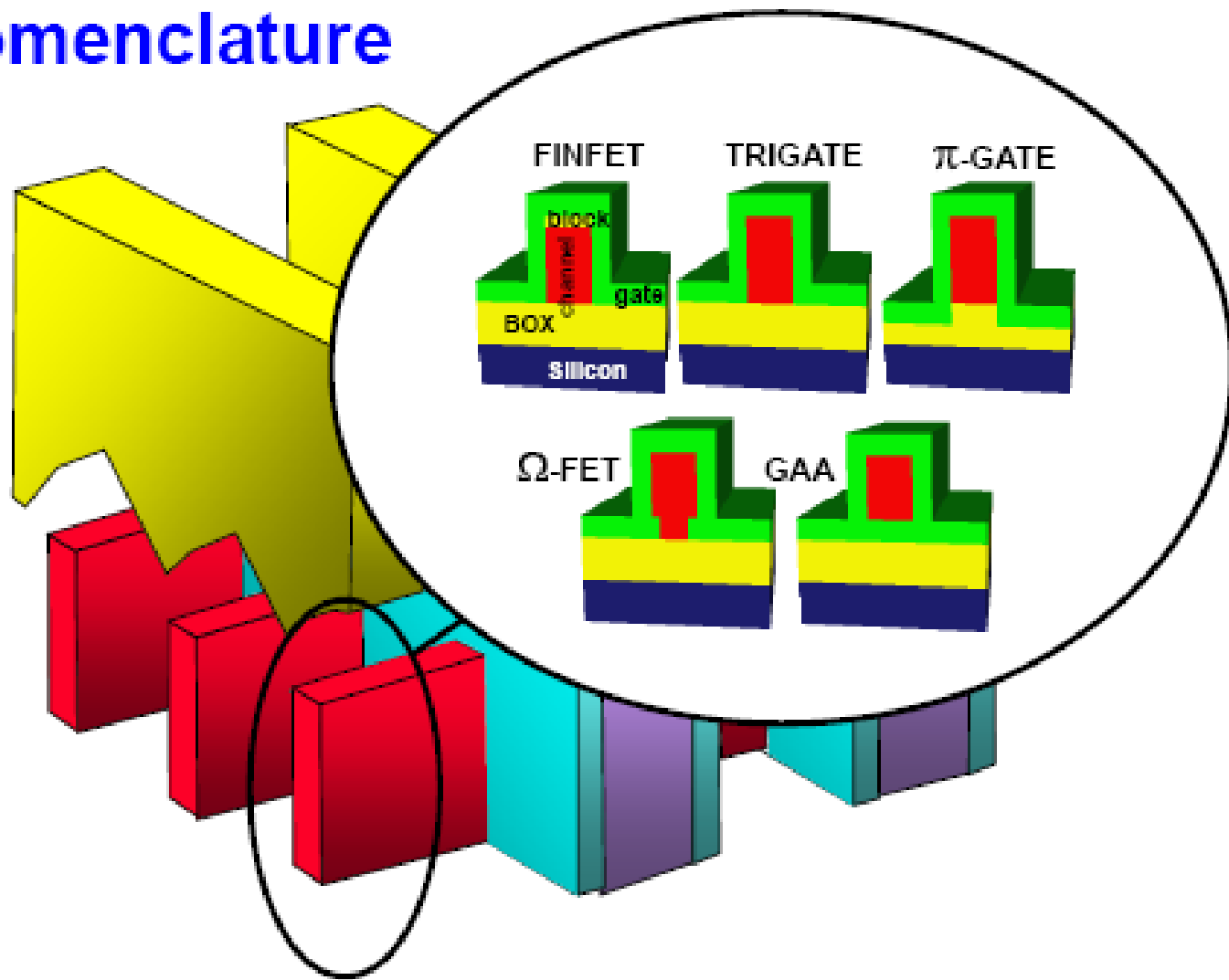
“2 Gates”

“3 Gates”

“Gate-all-Around”



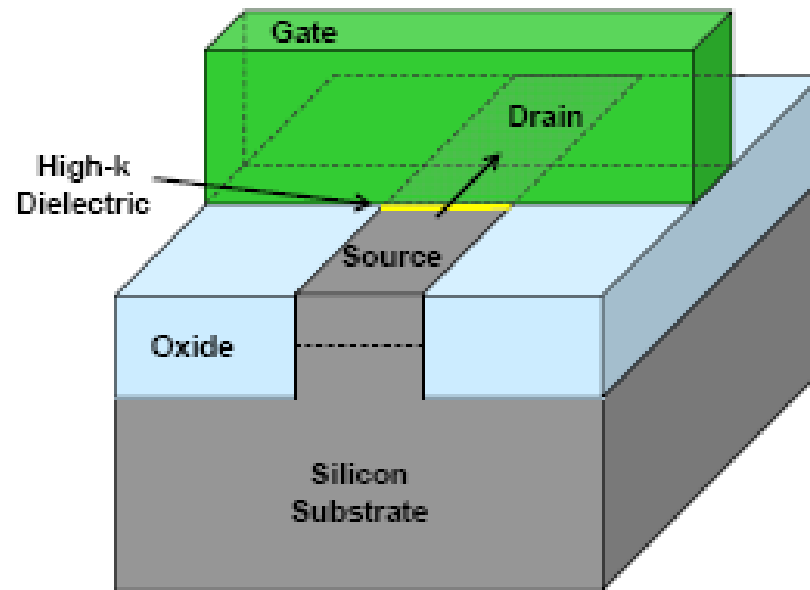
Nomenclature



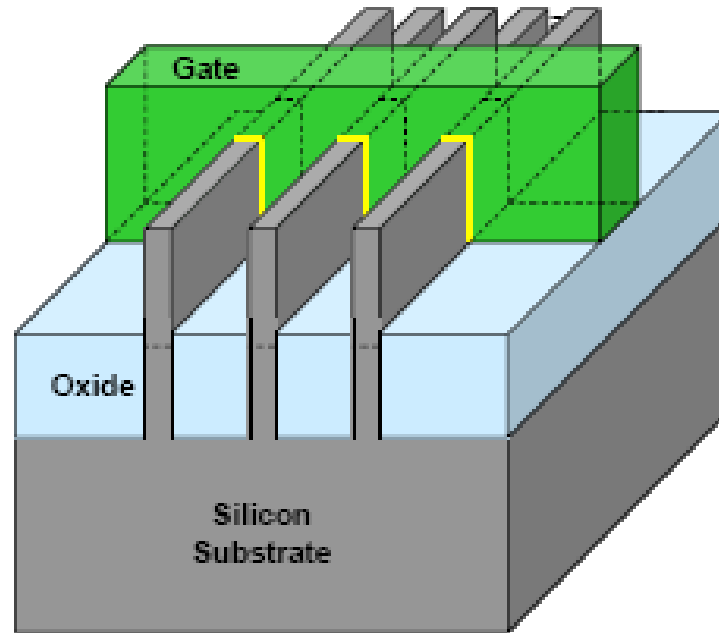
Kuhn: Tyndall 2011

14

Planar

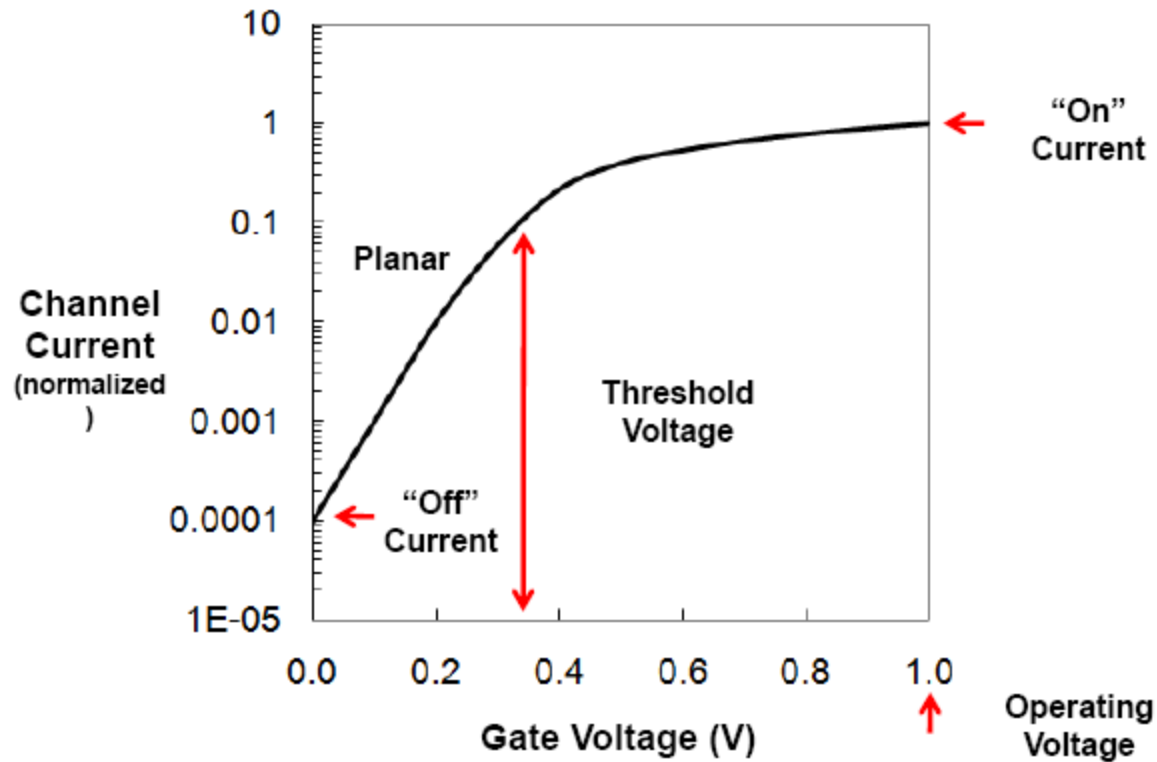


TriGate



Tri-Gate transistors can have multiple fins connected together to increase total drive strength

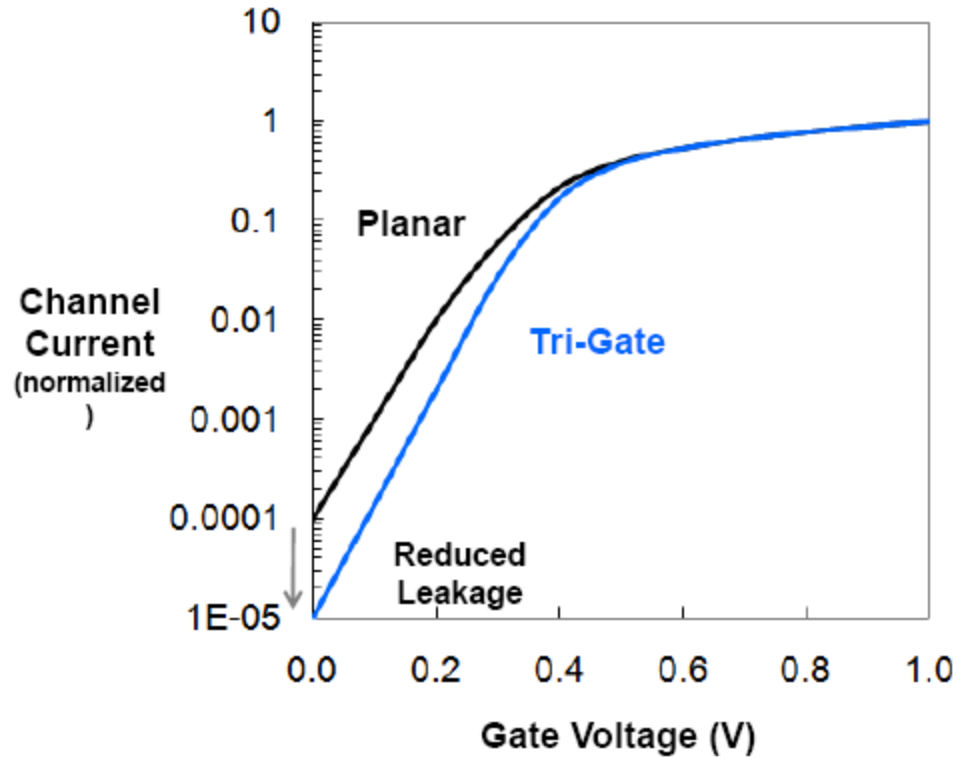
TriGate Electrostatics Benefits



Basic ID-VG

Kuhn: Tyndall 2011

TriGate Electrostatics Benefits

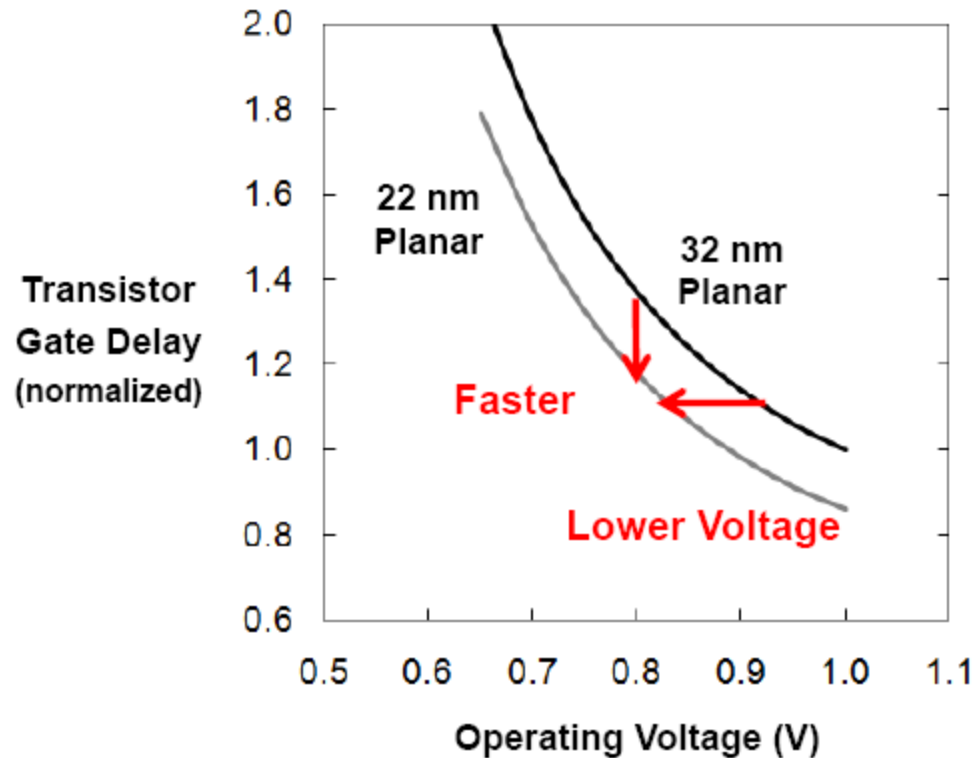


Good news:

Tri-gate short channel improvement → I_{off} improvement

Kuhn: Tyndall 2011

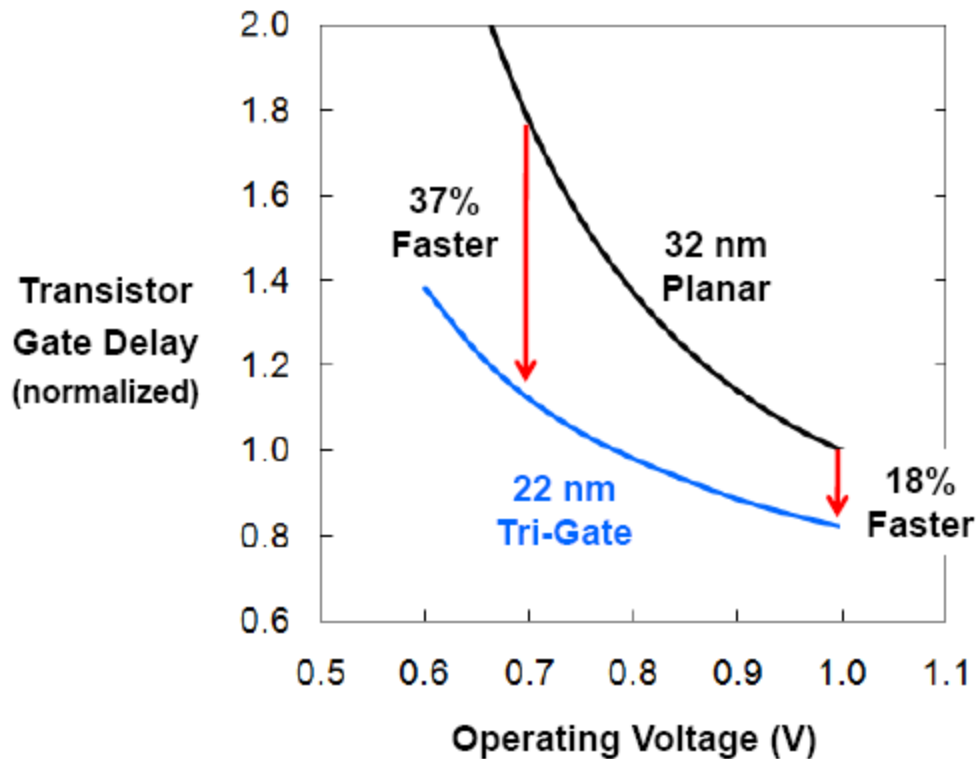
TriGate Electrostatics Benefits



22nm extension → similar ID-VG shape

Kuhn: Tyndall 2011

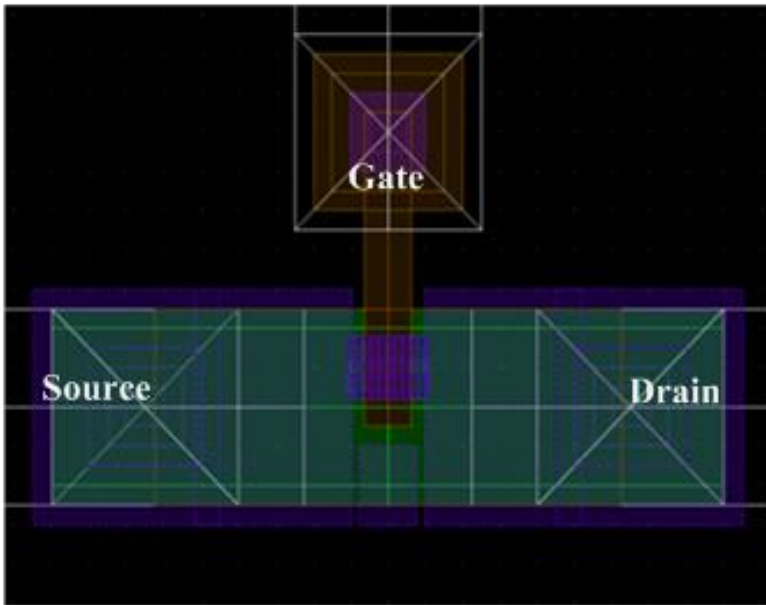
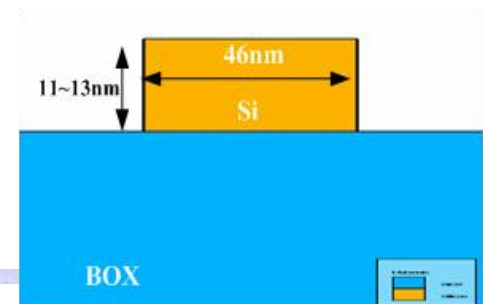
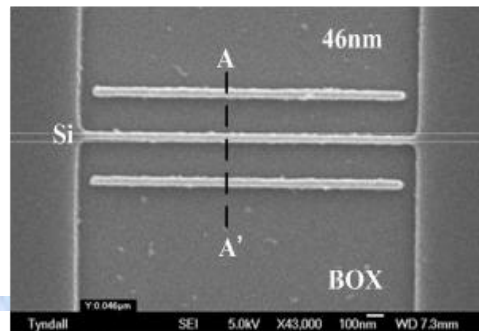
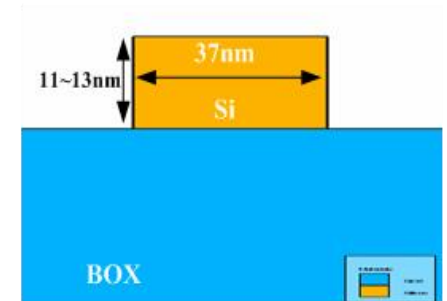
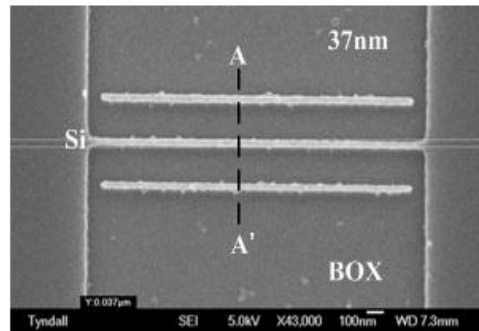
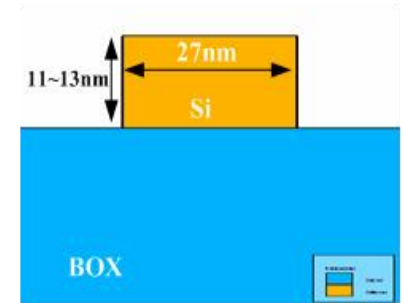
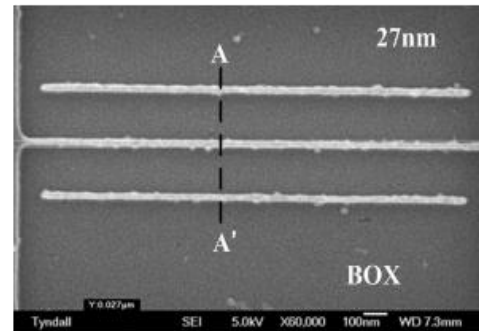
TriGate Electrostatics Benefits



EXCELLENT news: Improved performance at high voltage
and an *unprecedented* performance gain at low voltage

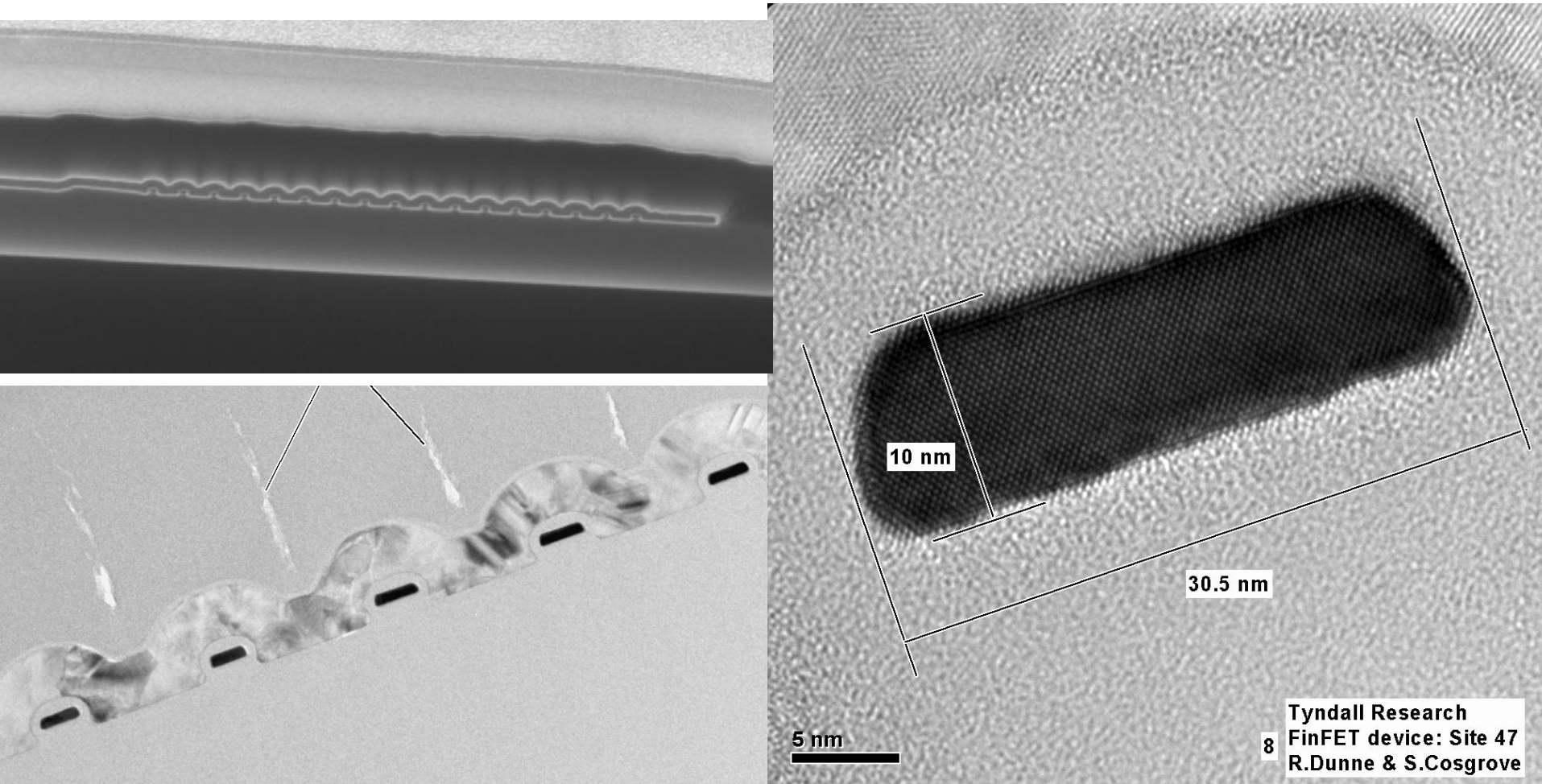
Kuhn: Tyndall 2011

E-beam Lithography and Process



Lay out view of fabricated device

Fabricated Device: TEM

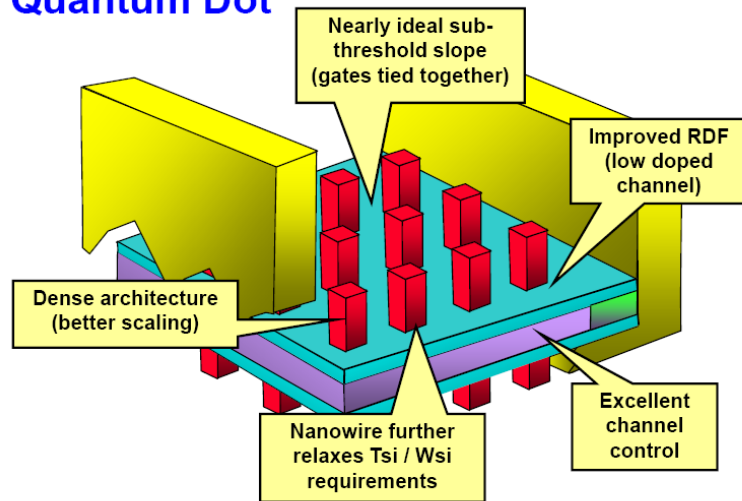


Future?

Nanowires and Quantum Dots

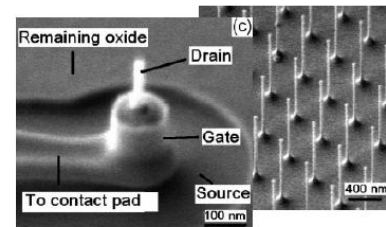
Nanowire / Quantum Dot

Benefits

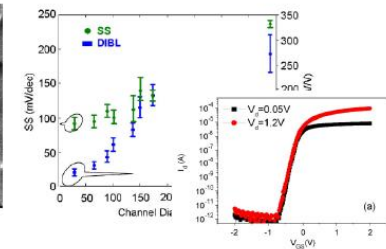


Kuhn: Tyndall 2011

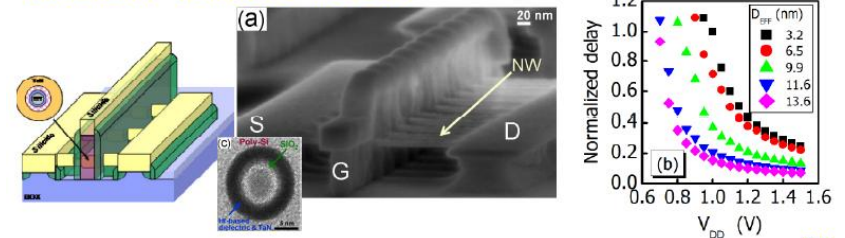
Yang – EDL 2008



Nanowire FETs



Bangsaruntip - IEDM 2009 / VLSI 2010

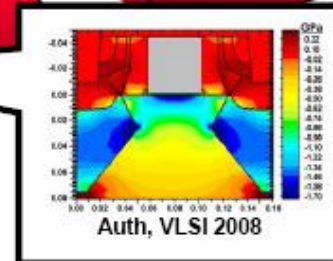
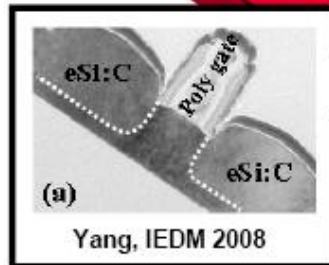
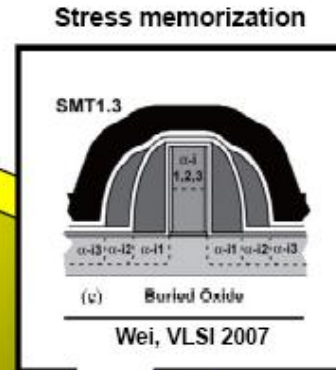
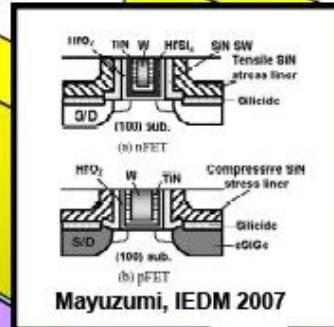
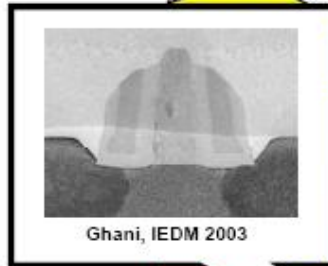


Kuhn: Tyndall 2011

33

Stress and Strain

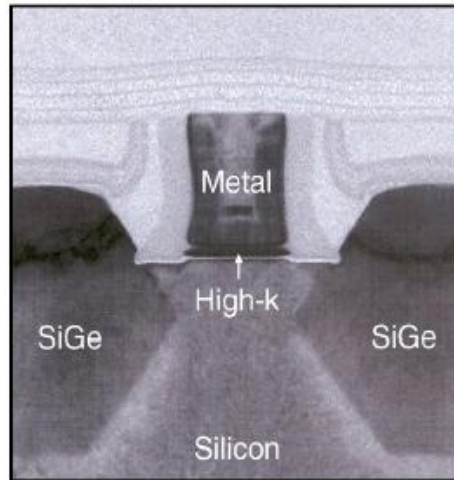
Strain in modern devices



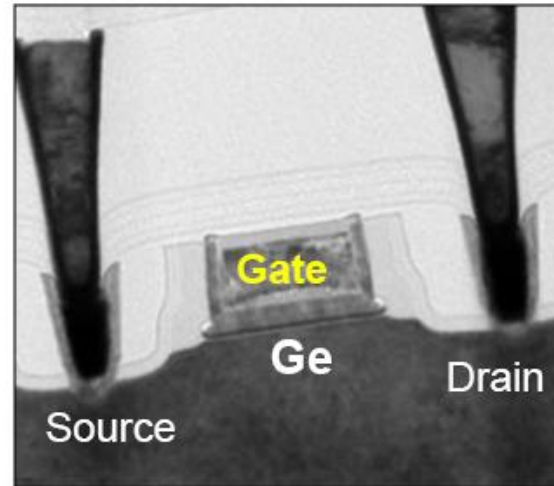
Kuhn: Tyndall 2011

New Materials

Si vs Ge MOSFETs



Intel 45nm HiK-MG Si device

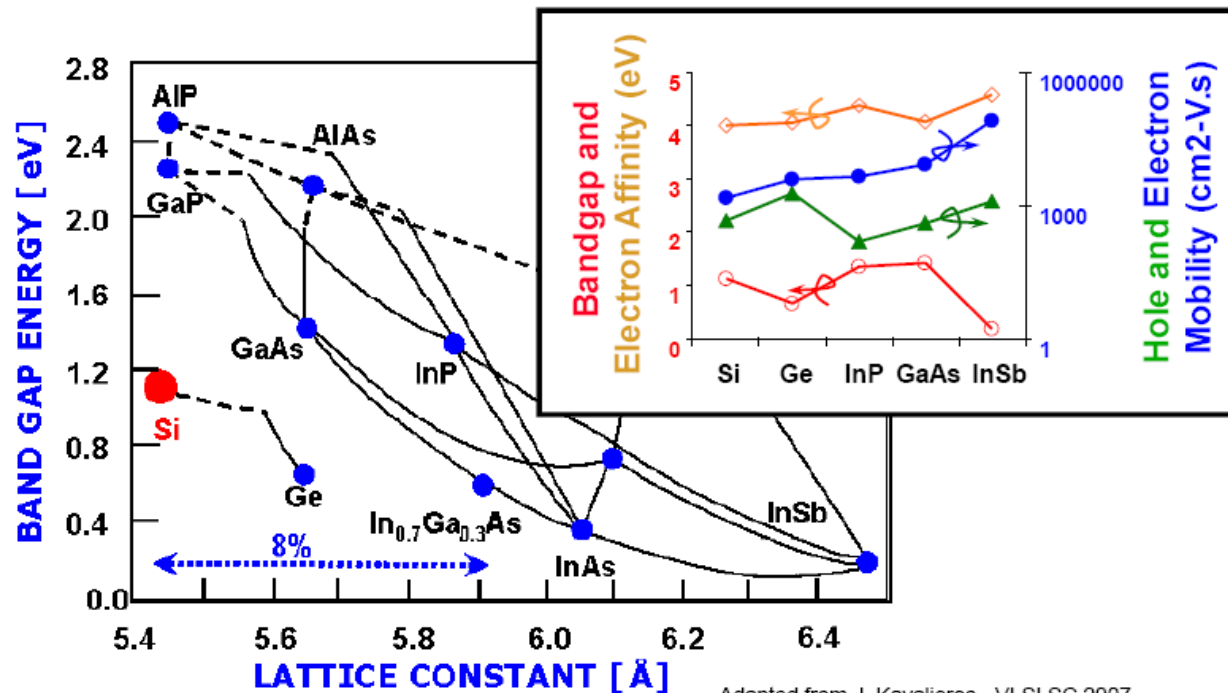


Intel HiK-MG Ge device

The introduction of manufacturable HiK-MG transistors has led to the reconsideration of Ge channels

III-V materials

III-V vs Ge: NMOS The Lure of High Mobility



Adapted from J. Kavalieros - VLSI SC 2007
K. Kuhn - ECS 2010

Kuhn: Tyndall 2011

54

Limit to visibility remains ~ decade

TECHNOLOGY GENERATION

45nm
2007

32nm
2009

22nm
2011

14nm
2013

10nm
2015

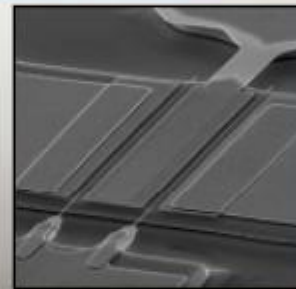
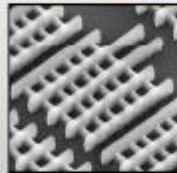
7nm
2017

Beyond
2020

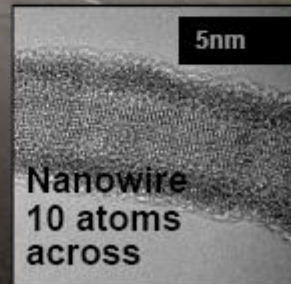
MANUFACTURING

DEVELOPMENT

RESEARCH

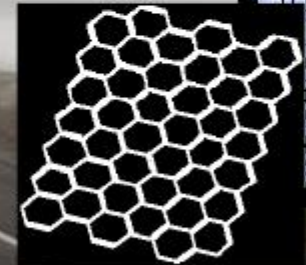


QW III-V Device



Nanowire
10 atoms
across

Carbon
Nanotube
~1nm diameter



Graphene
1 atom thick

Not to scale